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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

|             |  |   |                           |
|-------------|--|---|---------------------------|
| Applicant:  | Joseph M. Steigerwald                  | § |                           |
|             |  | § | Art Unit: 2815            |
|             |  | § |                           |
| Serial No.: | 10/722,801                             | § |                           |
|             |  | § |                           |
| Filed:      | November 26, 2003                      | § | Examiner: Sheila V. Clark |
|             |  | § |                           |
| For:        | Electrochemically Polishing Conductive | § | Atty Docket: ITL.0947US   |
|             | Films on Semiconductor Wafers          | § | P15971                    |
|             |  | § |                           |

Mail Stop **Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**REPLY TO PAPER NO. 0**

Sir:

In response to the office action mailed November 4, 2004, please amend the above-referenced patent application as follows:

Date of Deposit: January 25, 2005

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Cynthia L. Hayden*  
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